

Agilent 7900 ICP-MS

Specifications and Typical Performance



Raise your expectations with the 7900 ICP-MS

The Agilent 7900 ICP-MS rewrites the rules of ICP-MS. New technologies and a redesigned software platform combine to make the 7900 ICP-MS the world's most powerful, and most automated quadrupole ICP-MS.

Some key components, such as the RF generator and quadrupole mass analyzer, are shared with the field-proven 7700 Series ICP-MS and 8800 ICP-QQQ. However, the Agilent 7900 ICP-MS has been re-engineered from the bench up, with every component optimized for the demands of busy laboratories today, and in the future.



Agilent Technologies

Specifications

| Sample Introduction System | Peristaltic pump | 10-roller, 3 channels | |
|----------------------------|---|---|--|
| Sample Introduction System | Nebulizer | MicroMist (borosilicate glass) | |
| | | | |
| | Spray chamber | Scott-type double-pass (quartz) Controlled temperature range: -5 °C to +20 °C | |
| | Ultra High Matrix Introduction system (UHMI) | Optional | |
| Plasma | RF generator | Solid state digital drive 27 MHz Variable-frequency impedance matching 500 W to 1600 W | |
| | Torch | One-piece (quartz) 2.5 mm id injector ShieldTorch system | |
| | Torch position | Horizontal and vertical position: ±2 mm, in 0.1 mm steps Sampling depth: 3 to 28 mm, in 0.1 mm steps | |
| | Mass flow controllers (Ar) | 4: Plasma, Aux., Carrier, Make up/Dilution | |
| | 5th gas line for alternative carrier gas | Optional | |
| Interface | Sampling cone | 1 mm diameter orifice Standard: Ni-tipped with Cu base Optional: Pt-tipped with Cu base | |
| | Skimmer cone | 0.45 mm diameter orifice Standard: Ni Optional: Pt-tipped with Cu base | |
| lon Lens | Lens system | Extraction lens Off-axis Omega lens | |
| Octopole Reaction System | He (collision) cell gas line | Included | |
| (ORS) | H_2 (reaction) cell gas line | Optional | |
| | 3rd cell gas line (low- or high-flow rate) | Optional | |
| Mass Analyzer | Quadrupole | Frequency: 3 MHz Hyperbolic rod profile | |
| | Mass range | 2-260 u | |
| | Mass resolution | Variable from 0.3 u to 1.0 u | |
| | Typical mass calibration stability | < 0.05 u per day < 0.1 u per 6 months | |
| | Abundance sensitivity (at Cs) | Low mass side: $\leq 5 \times 10^{-7}$ | |
| | | High mass side: $\leq 1 \times 10^{-7}$ | |

| Detector | Configuration | Orthogonal Detector System (ODS) |
|---------------|--|---|
| | Detector | Dual-mode discrete dynode electron multiplier |
| | Dynamic range | 11 orders (0.1 cps to 10 Gcps) |
| | Minimum integration time | 100 µs |
| | Minimum dwell time (TRA mode) | 0.1 ms (no settling time) |
| Vacuum System | Configuration | Three-stage differential vacuum system |
| | Vacuum pump | Single split-flow turbo molecular pump Single external rotary pump |
| | Vacuum pump hose length | 1.5 m, 3 m (optional) |
| Software | Instrument contol software | ICP-MS MassHunter Workstation software |
| | User access control software | Optional |
| | Chromatographic software | Optional |
| | Single nanoparticle application module | Optional |
| | Intelligent sequencing software | Optional |
| | Three offline user licenses | Optional |

Accessories and Peripherals

| Autosamplers | Agilent SPS 4 Autosampler Agilent Integrated Autosampler (I-AS) |
|---------------------|---|
| Sample introduction | Integrated Sample Introduction System 3 PFA Inert Sample Introduction Kit Organic Solvent Introduction Kit Humidifier |
| Speciation kits | LC-ICP-MS Speciation Kits Arsenic Speciation Kit Chromium Speciation Kit Capillary LC Interface Kit GC-ICP-MS Interface |
| Peripherals | Water recirculator Water chiller Optional hood Quiet cover for rotary pump |

Instrument Performance

The factory shipping specifications that are confirmed at the factory represent minimum requirements for shipping approval. The actual performance of the Agilent ICP-MS is invariably much higher. The two tables below provide the typical performance of the Agilent 7900 ICP-MS, together with the factory shipping specifications.

| No Gas mode | | 7900 Factory Specifications ¹ | |
|---------------------------|--------------------------------------|---|-----------|
| Sensitivity (Mcps/ppm) | ⁷ Li | 55 | 140 |
| | ⁵⁹ Co | | 400 |
| | ⁸⁹ Y | 320 | 600 |
| | ¹¹⁵ In | | 700 |
| | ²⁰⁵ TI | 250 | 520 |
| | ²³⁸ U | | 720 |
| Background | <i>m/z</i> 9 | <1 cps | <0.3 cps |
| Detection limits | ⁰Be | <0.2 ppt | <0.05 ppt |
| | ¹¹⁵ In | <0.05 ppt | <0.02 ppt |
| | ²⁰⁹ Bi | <0.08 ppt | <0.02 ppt |
| Oxide | CeO/Ce | <1.5% | <1.8% |
| Doubly charged | Ce ²⁺ /Ce | <3% | <2.5% |
| Stability | 20 min | <2.0% RSD | <1.0% RSD |
| | 2 hr | <3.0% RSD | <1.2% RSD |
| lsotope ratio precision | ¹⁰⁷ Ag/ ¹⁰⁹ Ag | <0.1% RSD | <0.1% RSD |

| He Gas mode | | 7900 Typical Performance ² |
|--|-------------------------------------|--|
| Sensitivity (Mcps/ppm) | ⁵⁹ Co | 65 |
| Background | <i>m/z</i> 9 | <0.2 cps |
| Interference reduction factor ³ | ⁵⁹ Co/ ⁵¹ ClO | >30 |
| Oxide | CeO/Ce | <0.5% |
| Detection limits ³ | ⁷⁵ As | <5 ppt |

1. 7900 Factory Shipping Specifications. These specifications are detailed in the Agilent publication: Agilent 7900 ICP-MS, Specifications (Publication number: 5991-3779EN).

 $\ensuremath{\mathbf{2}}$. The typical performance values are not checked during the standard installation.

3. Performed in a matrix of 2% HNO₃ + 0.5% HCl.

Site Requirements and Safety

Dimensions

| Mainframe | Width | 730 mm (main cabinet, excluding peri-pump) |
|----------------------------|--------|--|
| | Depth | 600 mm (main cabinet, excluding power cord) |
| | Height | 595 mm (main cabinet, excluding exhaust chimney) |
| | Weight | 100 kg |
| Largest shipping container | Width | 1,020 mm |
| | Depth | 1,120 mm |
| | Height | 1,000 mm |
| | Weight | 148 kg |

Environmental

| Operating temperature | Range | 15–30 °C |
|-----------------------|-------------------|---|
| | Rate of change | <2 °C/hr (max. change 5 °C) |
| Operating humidity | Range | 20-80% (non-condensing) |
| | | |
| Utilities | | |
| Electricity supply | Voltage | Single Phase, 200-240 V, 50/60 Hz |
| | Current | 30 A |
| Cooling water | Inlet temperature | 15-40 °C |
| | Minimum flow rate | 5 L/min |
| | Inlet pressure | 230-400 kPa |
| Argon gas supply | Minimum purity | 99.99 % |
| | Maximum flow rate | 20 L/min |
| | Supply pressure | 500-700 kPa |
| Cell gas supply | Minimum purity | 99.999% |
| | Maximum flow rate | 12 mL/min for He and 10 mL/min for H_2 |
| | Supply pressure | 90-130 kPa for He 20-60 kPa for H ₂ |
| Exhaust duct | Vent Type | Single vent, 150 mm diameter |
| | Flow rate | 5-7 m³/min |
| | | |

Regulatory Compliance

- Safety IEC 61010-1:2001 / EN 61010-1:2001 IEC 61010-2-061:2005 / EN 61010-2-061:2003 IEC 61010-2-081:2001+A1:2003 / EN 61010-2-081:2002+A1:2003 Canada: CAN/CSA C22.2 No. 61010-1-04 Canada: CAN/CSA C22.2 No. 61010-2-061-04 Canada: CAN/CSA C22.2 No. 61010-2-081-04 USA: UL 61010-1 (2nd Edition)
- EMC IEC 61326-1:2012 / EN 61326-1:2013 Canada: ICES-001:2006
- ISO Manufactured at an ISO 9001 and ISO 14001 certified facility

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